



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Katsuhisa YUDA et al.

Appl. No.: 09/818,972

Art Unit: 1763

Filed: March 27, 2001

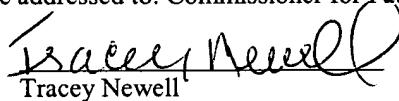
Examiner: CROWELL, Anna M.

For: METHOD OF FORMING SILICON  
OXIDE FILM AND FORMING  
APPARATUS THEREOF

Atty Docket: GOM-02001

**CERTIFICATE OF MAILING**

I hereby certify that the foregoing document is being deposited with the United States Postal Service as first class mail, postage prepaid, "Post Office to Addressee", in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on April 23, 2004.



Tracey Newell

**AMENDMENT AND RESPONSE TO OFFICE ACTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This paper is being provided in response to the Final Office Action dated February 5, 2004, for the above-captioned U.S. patent application.

**Amendments to the Claims** are listed beginning on page 2 of this paper.

**Remarks** begin on page 8 of this paper.

It is not believed that extensions of time or fees for net addition of claims are required, beyond those which may otherwise be provided for in documents accompanying this paper. However, in the event that additional extensions of time are necessary, then such extensions of time are hereby petitioned under 37 C.F.R. § 1.136(a), and any fees required for consideration of this paper (including fees for net addition of claims) are authorized to be charged in two originally-executed copies of an Amendment Transmittal Letter filed herewith

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